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Attorney Docket no: SEL 246

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Koichiro TANAKA)
Serial No.: 09/812,529)
Filed: March 20, 2001)
For: Method of Manufacturing A Semiconductor)
Device)
Examiner: R. Booth)
Art Unit: 2812)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:
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D.C. 20231 on December 20, 2002
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Rachelle Hammerquist
Name of applicant, assignee, or Registered Rep.
Rachelle Hammerquist 12-20-02
Signature Date

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Commissioner for Patents
Washington D.C. 20231

AMENDMENT B

In furtherance of the Notice of Allowance of September 23, 2002, a RCE and IDS being submitted herewith, please amend the above-identified application as follows:

IN THE CLAIMS:

Please add the following new claims:

14 (New). A method of manufacturing a semiconductor device, comprising:

forming an amorphous semiconductor film over a substrate;

irradiating the amorphous semiconductor film with a first laser beam to form a first crystalline semiconductor film; and

irradiating the first crystalline semiconductor film with a second laser beam to form a second

B1W
C1W